

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	)	
Koichiro TANAKA	)	Confirmation No. 9528
Application No. 10/769,820	)	Examiner: Samuel Heinrich
Filed: February 3, 2004	)	Group Art Unit: 1725
For: LASER IRRADIATION STAGE, LASER	)	
IRRADIATION OPTICAL SYSTEM, LASER	)	
IRRADIATION APPARATUS, LASER	)	
IRRADIATION METHOD, AND METHOD OF	)	
MANUFACTURING A SEMICONDUCTOR	)	Date: October 17, 2007
DEVICE	)	

**AMENDMENT**

United States Patent and Trademark Office  
Customer Service Window, Mail Stop AF  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

In response to the Office Action mailed July 17, 2007, please amend the above-identified patent application as follows.

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 10 of this paper.